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(54) Title: METHOD TO CREATE THREE-DIMENSIONAL IMAGES OF SEMICONDUCTOR STRUCTURES USING A FOCUSED ION BEAM DEVICE AND A SCANNING ELECTRON MICROSCOPE

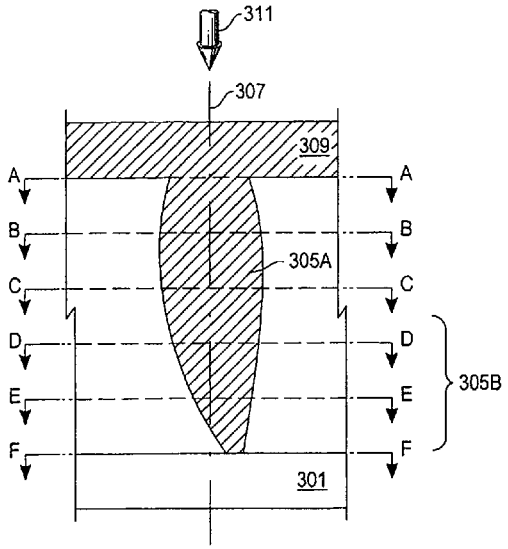


Fig. 3B

(57) Abstract: A disclosed method produces an image of one or more fabricated features by iteratively producing a cross-section of the features. The method includes milling a surface proximate to the one or more fabricated features where the surface being milled is substantially parallel to a layer in which the feature is located. At each milling step, top-down imaging of the one or more fabricated features produces a plurality of cross-sectional images. Each of the plurality of cross-sectional images is reconstructed into a representation of the fabricated feature.

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